| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|----------|------|---|--------------------|---------------------|---------|------------------|
| S1 | 806 | wafer near3 cleaning.clm. | USPAT; EPO; JPO | OR | ON | 2005/02/22 17:39 |
| S2 | 22 | S1 and pivot\$5.clm. | USPAT; EPO; JPO | OR | ON · | 2005/02/22 17:37 |
| S3 | 218 | wafer near5 roll\$5.clm. | USPAT; EPO; JPO | OR | ON | 2005/02/22 17:39 |
| 54 | 4 | S3 and ((clamp\$5 force pressure) near3 (test\$5 detect\$5 sens\$5 estimat\$5 evaluat\$5 determin\$5 measur\$5 transducer cell meter gauge monitor\$5)).clm. | USPAT; EPO; JPO | OR | ON | 2005/02/22 17:45 |